



# First-Principles Study for ALD of MoS<sub>2</sub>



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## 1. Introduction/Background

### Atomic layer deposition (ALD)

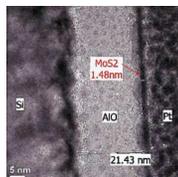
- ALD is a method for thin-film deposition with atomic precision.
- Volatile gas phase precursors allow lower reaction temperatures.
- Precursors are introduced sequentially and are self-limiting.

### Molybdenum disulfide (MoS<sub>2</sub>)

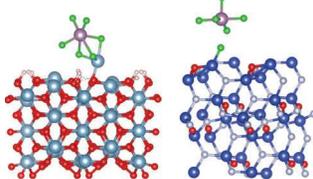
- 2D-MoS<sub>2</sub> is a semiconductor with a direct band gap of 1.8 eV [2].
- Applications in microelectronics, photovoltaics, and batteries [2].
- Deposited via ALD with molybdenum hexafluoride (MoF<sub>6</sub>) and hydrogen sulfide (H<sub>2</sub>S) precursors [1].

### Challenges with ALD of MoS<sub>2</sub>

- Difficult to study *in situ*.
- Relatively new and unknown chemistry.
- MoF<sub>6</sub>-substrate interactions are unknown.



Above: Transmission electron microscope images of MoS<sub>2</sub> deposited on Al<sub>2</sub>O<sub>3</sub> by ALD [1]. Below: Model of a single MoF<sub>6</sub> on hydroxylated Al<sub>2</sub>O<sub>3</sub> (left) and Si<sub>2</sub>N<sub>2</sub>O (right) surfaces.



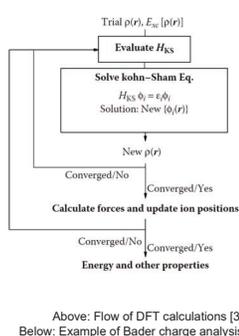
## 2. Project Goals and Methods

### Project Goals

- Understand *role of hydroxyl groups* (OH) on Al<sub>2</sub>O<sub>3</sub>, Si<sub>2</sub>N<sub>2</sub>O, and TiO<sub>2</sub> substrates with a *single MoF<sub>6</sub> precursor*.
- Explain *bonding and reduction* mechanisms during first MoF<sub>6</sub> half-cycle.

### Density functional theory (DFT)

- DFT is a first-principles computational modeling method (based on quantum mechanics rather than classical mechanics or empirical data).
- Calculates ground-state properties of a system.
- Less than 1,000 atoms in DFT modeled systems [3].
- We used the Vienna Ab initio Simulation Package (VASP) to implement DFT [4].



### Bader charge analysis

- Bader charge analysis creates Bader volumes from "zero-flux surfaces" around each atom [5].
- Using VASP output, it can determine the valence electron density within each Bader volume.
- Quantifies donation or acceptance of electron density for each atom in a system.

Atom #	Initial valence electrons	Bader charge	Δ valence electrons
Al11	3	0.56	-2.44

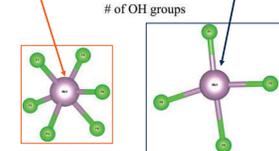
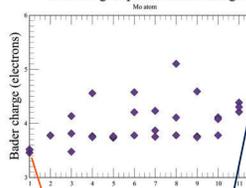
## 3. Results

### Bader charge analysis of MoF<sub>6</sub> on hydroxylated Al<sub>2</sub>O<sub>3</sub>

- A single MoF<sub>6</sub> was placed on Al<sub>2</sub>O<sub>3</sub> surfaces at varying hydroxyl concentrations.

**Observation:**  
OH groups increase the Mo atom's local electron density indirectly.

# of OH groups vs. Bader charge



MoF<sub>6</sub> on Al<sub>2</sub>O<sub>3</sub> with 1 OH group: minimal electron localization (small Bader charge) corresponds to +6 oxidation state.  
MoF<sub>6</sub>, 12 OHs: Large Bader charge corresponds to +4 oxidation state.

- A change in the oxidation state of Mo from +6 to +5, +4, and +3 is evident by increased local electron density [6].

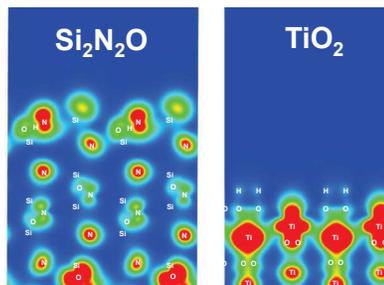
Legend

Mo	F	Al	O	H	N	Si

### Si<sub>2</sub>N<sub>2</sub>O and TiO<sub>2</sub> surface models

Substrate	Surface Energy (eV/Å)
TiO <sub>2</sub> (100)	0.0237
TiO <sub>2</sub> (110)	0.0433
TiO <sub>2</sub> (111)	0.0596
Si <sub>2</sub> N <sub>2</sub> O (100)	0.1972
Si <sub>2</sub> N <sub>2</sub> O (110)	0.2815
Si <sub>2</sub> N <sub>2</sub> O (111)	0.1181

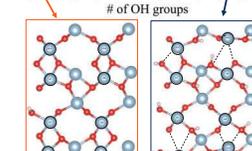
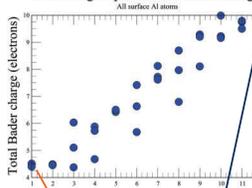
Surface formation energies of non-hydroxylated TiO<sub>2</sub> and Si<sub>2</sub>N<sub>2</sub>O surfaces cleaved from bulk at various Miller indices: (100), (110), and (111).



Partial charge densities of Si<sub>2</sub>N<sub>2</sub>O 110 (left) and TiO<sub>2</sub> 110 (right) surfaces, fully hydroxylated.

**How?**  
OH groups break Al-O bonds.

# of OH groups vs. total Bader charge



Top-down view of Al<sub>2</sub>O<sub>3</sub> surface with 1 OH. Surface Al atoms outlined. MoF<sub>6</sub> omitted for clarity.  
Same surface with 12 OH. Dashed lines represent Al-O bonds broken by OH.

- This frees up Al electrons so they can form Al-F bonds.
- Results in separation of F atoms from MoF<sub>6</sub>.
- Electrons from broken Mo-F bonds then localize to the Mo atom.

## 4. Analysis

### MoF<sub>6</sub> on hydroxylated Al<sub>2</sub>O<sub>3</sub>

- Reducing Mo to an oxidation state of +4 may increase reaction favorability.
- We predict that the oxidation state of Mo in the product, MoS<sub>2</sub>, is +4.
- However, the oxidation state of Mo in MoF<sub>6</sub> is +6.
- Similar molybdenum sulfide reactions are proposed to be most energetically favorable when Mo does not change oxidation state during the reaction [1].
- Mo-O bonds were not observed on OH groups, so more OH → fewer Mo-O bonds.
- Mo-O bonds are known to form in experiment [1].
- Minimizing these bonds could make the film/substrate boundary cleaner.

### Si<sub>2</sub>N<sub>2</sub>O and TiO<sub>2</sub> substrates

- On (110) and (111) Si<sub>2</sub>N<sub>2</sub>O, hydroxylation increases partial charge density of O atoms.
- However, on (100) Si<sub>2</sub>N<sub>2</sub>O, hydroxylation decreases O atom partial charge density.
- Investigation of TiO<sub>2</sub> surfaces' partial charge densities is in progress.
- Initial results show that hydroxyl affect these partial charge densities as well.

## 5. Conclusions/Future Work

### Conclusions

- Based on our analysis, we predict increased reaction favorability and cleaner film/oxide interfaces by maximizing OH concentration because:
  - OH groups break Al-O bonds on the Al<sub>2</sub>O<sub>3</sub> surface and reduce the oxidation state of a deposited Mo atom.
  - OH groups hinder Mo-O interactions.
- Hydroxylation changes Si<sub>2</sub>N<sub>2</sub>O and TiO<sub>2</sub> surface O chemistry in different ways depending on the surface: (100), (110), or (111).

### Future work

- Determine if surface decomposition of Al<sub>2</sub>O<sub>3</sub> has any effects on material properties.
- Bader charge analysis of two or more MoF<sub>6</sub> molecules on Al<sub>2</sub>O<sub>3</sub>.
  - Preliminary results indicate that surface chemistry may vary with more MoF<sub>6</sub>.
- Add H<sub>2</sub>S to various MoF<sub>x</sub> species and calculate reaction energy.
  - This will provide insight on the relation between oxidation states and reaction energy.
- Simulate ALD of MoS<sub>2</sub> on Si<sub>2</sub>N<sub>2</sub>O and TiO<sub>2</sub> surfaces.
  - Investigate the mechanism by which hydroxylation increases O partial charge on some structures but decreases it on others.

## 6. Acknowledgements

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### References

- Letourneau, Steven Payonk, "Molybdenum Sulfide Prepared by Atomic Layer Deposition: Synthesis and Characterization" (2018). *Boise State University Theses and Dissertations*. 1397. doi:10.18122/td/1397/boisestate
- Li, Xiao, and Hongwei Zhu. "Two-Dimensional MoS<sub>2</sub>: Properties, Preparation, and Applications." *Journal of Materials*, vol. 1, no. 1, Mar. 2015, pp. 33-44. DOI.org (Crossref), doi:10.1016/j.jmat.2015.03.003.
- Lee, June Gunn. *Computational Materials Science: An Introduction*. Second edition. CRC Press, Taylor & Francis Group, CRC Press is an imprint of the Taylor & Francis Group, an informa business, 2017.
- G. Kresse, *Phys. Rev. B* 54, 11 (1996).
- W. Tang, et al., *Journal of Physics: Condensed Matter* 21, 084204 (2009).
- Posyasaev, Sergei, et al. "Oxidation States of Binary Oxides from Data Analytics of the Electronic Structure." *Computational Materials Science*, vol. 161, Apr. 2019, pp. 403-14. DOI.org (Crossref), doi:10.1016/j.commatsci.2019.01.046.

